

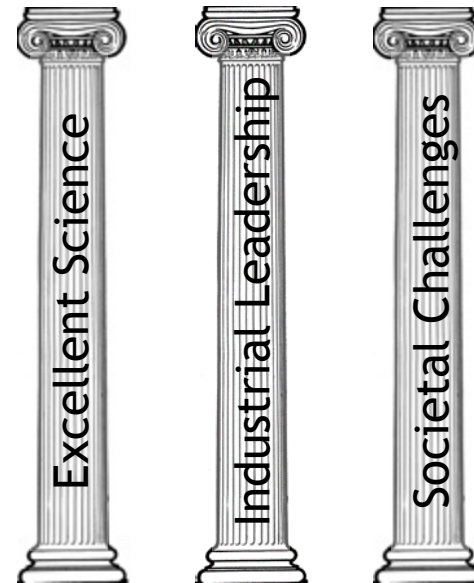
Infrastructure underpinning advanced nanoelectronics design



Tyndall team: Nicolas Cordero, Julie Donnelly, Jim Greer, Graeme Maxwell, Paul Roseingrave

Imec team: Thomas Chiarella, Jerome Mitard, Abdelkarim Mercha, Valentina Terzieva

Leti team: Olivier Faynot, David Holden, Gilles Reimbold



- A changing business and design costs
- The problem statement
- ASCENT: the offering
- Where we are now
- Looking further ahead

“Today, your cell phone has more computer power than all of NASA back in 1969, when it placed two astronauts on the moon.”

Michio Kaku, Physics of the Future:

How Science Will Shape Human Destiny and Our Daily Lives By the Year 2100



mobile phone

☐ \$200 - \$800

~ 80 **B**illion
operations per second

Memory: 2 **B**illion words

Power: 2 - 6 W

Weight: ☐ 150 **g**rams

Makes phone calls

Cray - 1

☐ \$9,000,000

~ 160 **M**illion
operations per second

Memory: 1 **M**illion words

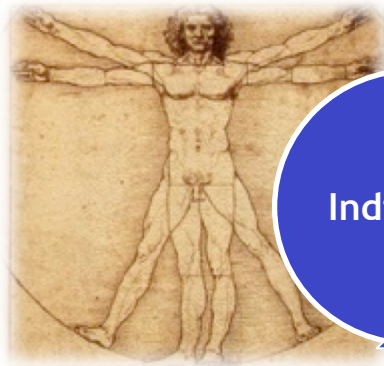
Power: 115 **k**W

Weight: 5.5 **t**ons

Doesn't make phone calls



The infrastructure is in place



Individual

Smart
Device

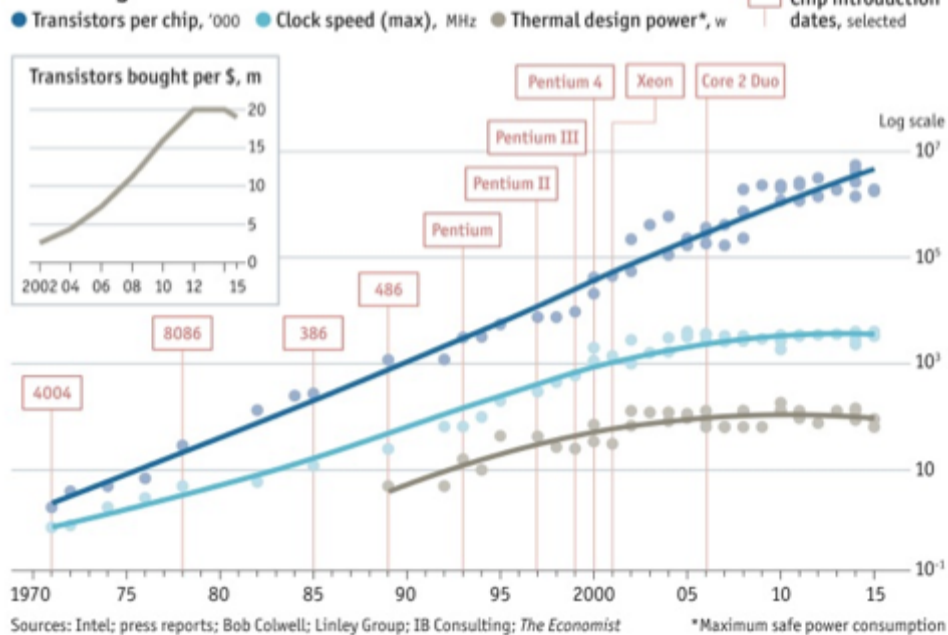
Physical
World

Cloud

> 25,000,000,000 connected
devices by 2020
(Gartner report)
- or approx. 3 devices for
every man, woman and child
on earth
'Internet of Things'

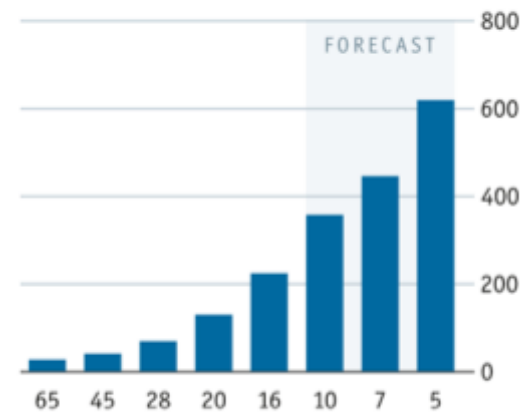
Cost/performance returns by scaling diminishing
Cost to achieve tape out on new nodes increasing

Stuttering



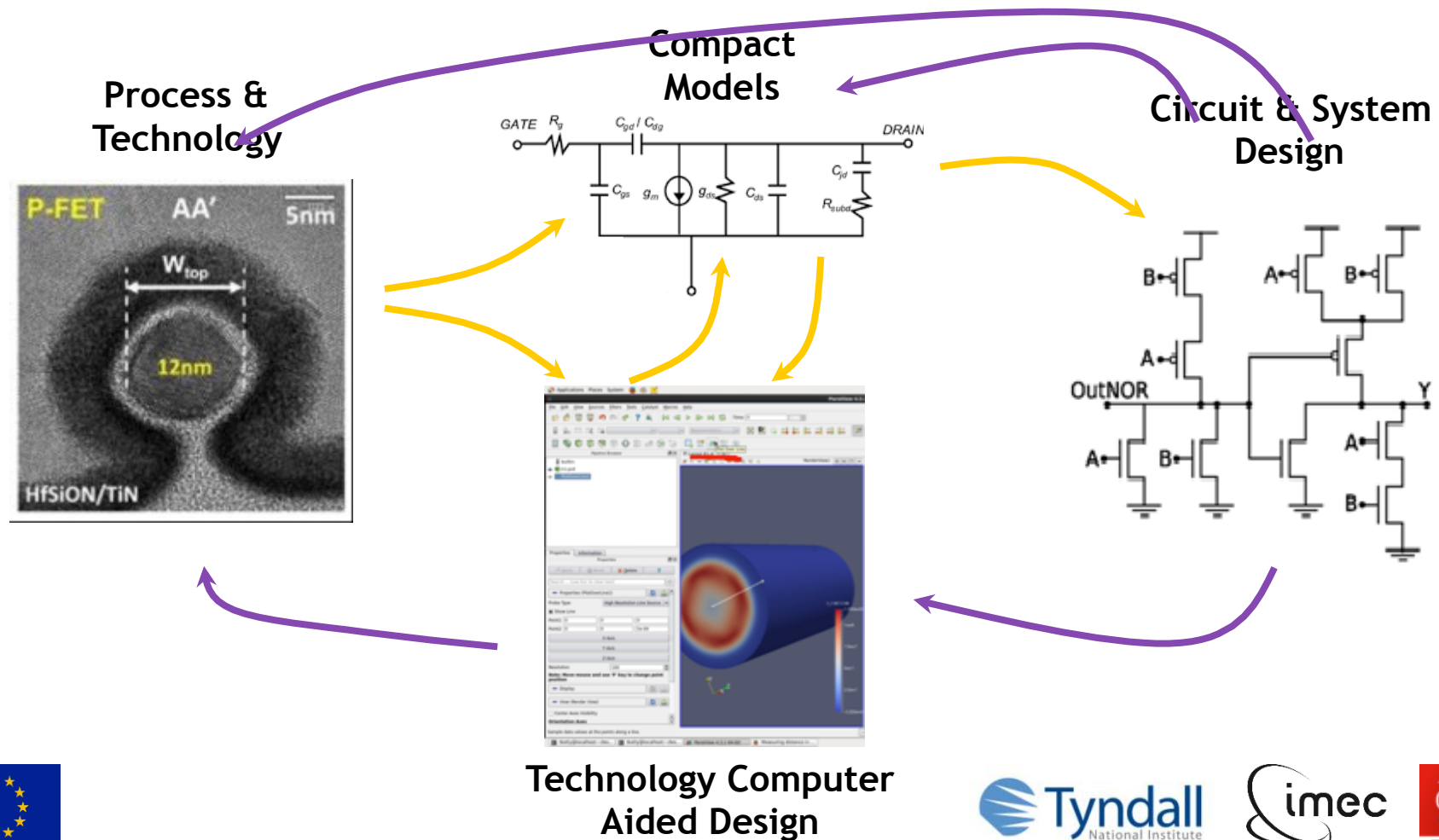
This can't go on

Design cost by chip component size in nm, \$m

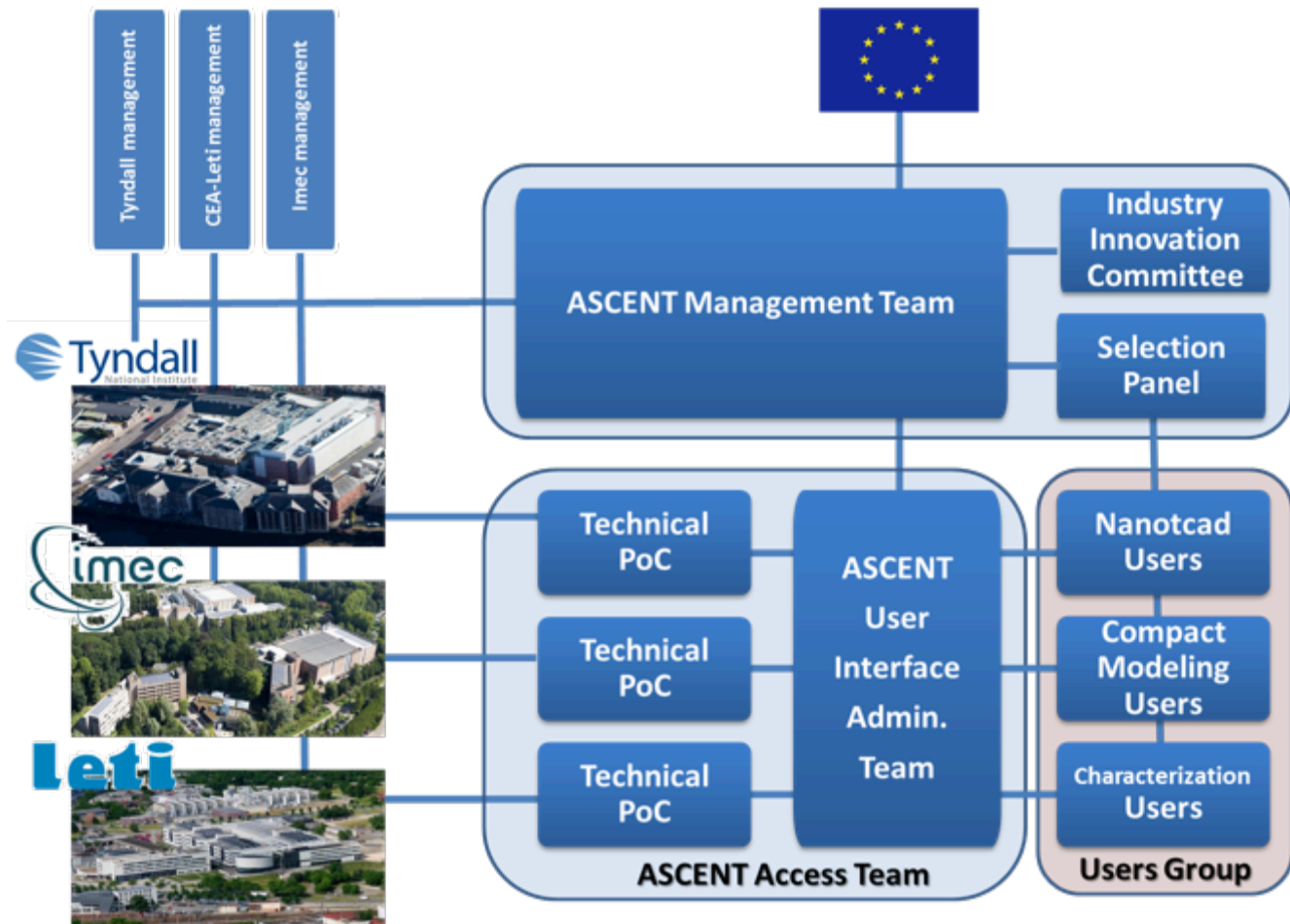


Source: IB Consulting

... an infrastructure for the **global** nanoelectronics modeling, characterization, and design communities



The combined resources of Tyndall, Imec and CEA-Leti nanofabrication capabilities and electrical characterization facilities integrated into a single research infrastructure present a truly unique opportunity

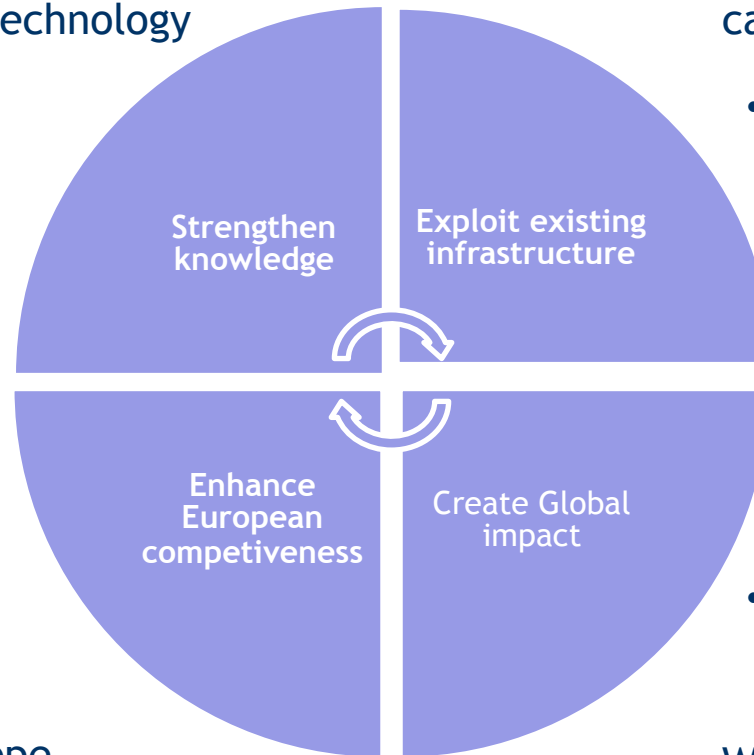


ASCENT will:

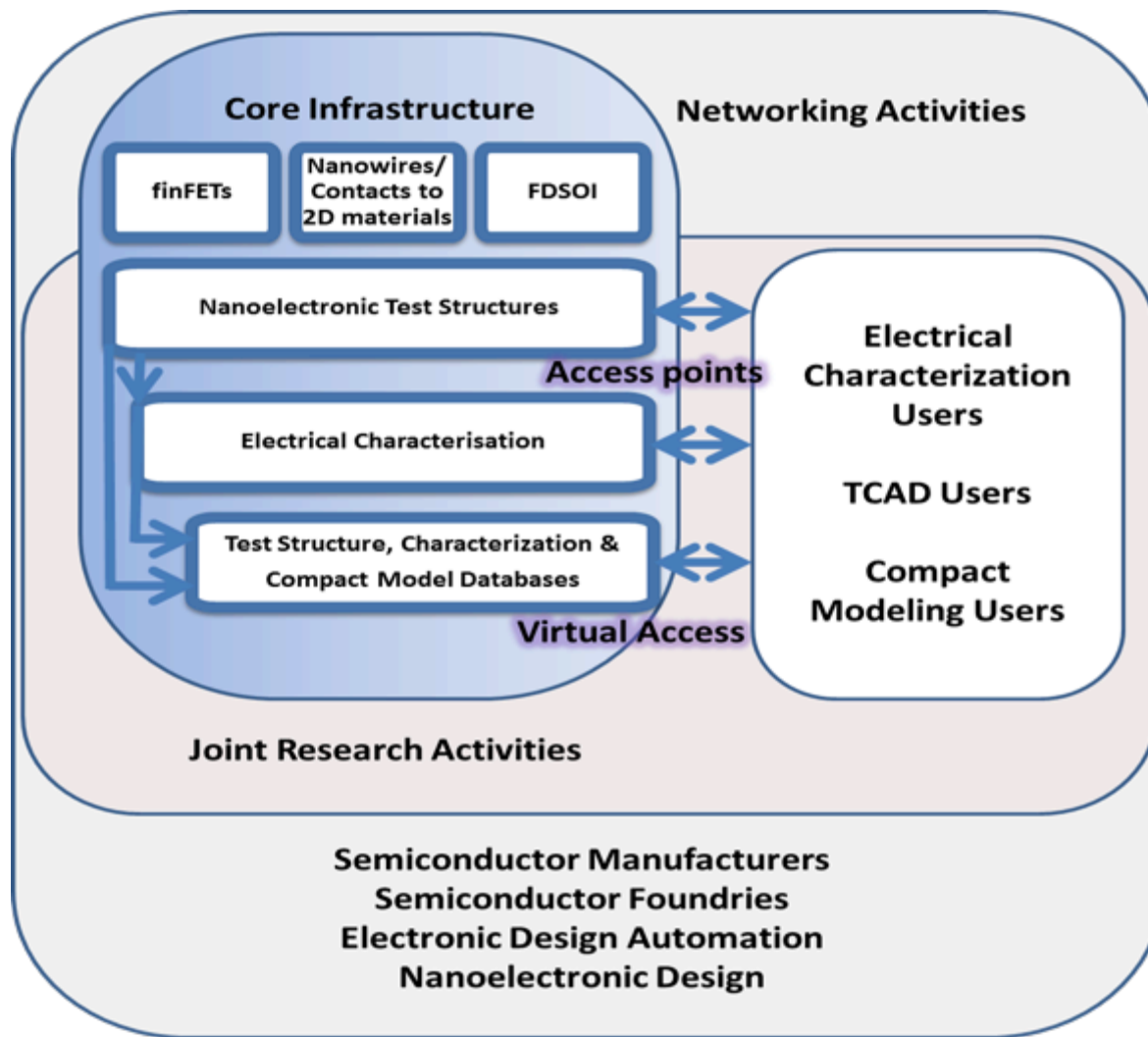
- Leverage Europe's Unique advantage in nanofabrication to strengthen modeling and characterisation research community
- Accelerate development of advanced models at scales of 14nm and below
- Provide characterisation community with access to advanced test chips, flexible fabrication and advanced test and characterisation equipment
- Make project outputs available and easily accessible to nanoelectronics research community

ASCENT offers simplified access
to
advanced technology and research infrastructure

- Enable researchers to realise innovative ideas at forefront of technology
- Benchmarking new developments against state-of-the-art technology
- Anchor advanced modelling, design and manufacturing in Europe
- Enables delivery of first-mover advantage



- Exploit over €2 billion capital investment
 - Assemble critical mass of people, knowledge and investment
- Ambition to maintain world leadership
- World-wide open door and dissemination policy



Users Committee

- **George Angelov**
 - TU Sofia
- **Asen Asenov**
 - Uni Glasgow
- **Olivier Faynot**
 - CEA
- **Francisco Gamiz**
 - Uni Granada
- **Benjamin Iñiguez**
 - Uni Rovira i Virgili
- **Andreas Schenk**
 - ETH

Innovation Committee

- **Bernie Capraro**
 - Intel
- **Patrick Drennan**
 - Qualcomm
- **Ronald Gull**
 - Synopsys
- **Dominique Thomas**
 - ST Microelectronics

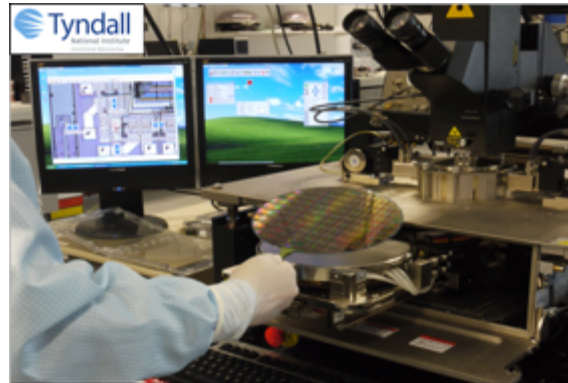
The Access Providers



State-of-the-art 14 nm bulk FDSOI CMOS

Advanced transistor and interconnect test structures

Electrical & nano-characterization platforms



Fabrication facilities for nanowires & 2D materials

Advanced nanowire and nano-electrode test structures

Electrical & nano-characterization platforms




State-of-the-art 14 nm FinFET CMOS


Advanced transistor and interconnect test structures


Electrical & nano-characterisation platforms

www.ascent.network


 **ascent** - ASCENT Virtual Access Data
European Nanoelectronics Access


HOME ► MY COURSES ► ASCENT ► VA_DATA


 News forum


 Feedback Forum/Blog


finFET_imec
Data for imec's finFET technology

 Bulk finFET DESCRIPTION

 Bulk finFET DATA

 Datafiles - Full Curves: IDVG/IDVD on NFIN/PFIN

 Bulk finFET Matching DATA

 Matching Data - Full curves and VT

FDSOI_Leti
Data for Leti's FDSOI

 PDK LETI FDSOI 14nm

 Design Kit and Documentation

Sign up and find out more



Sign-up Form

Please fill your details below. By signing up, you become a member of the ASSENT network. Members will receive specific information by email on ASSENT technologies, details about upcoming events and news.

For more detailed technical enquiry regarding access, please fill the [ASSENT Enquiry Form](#)

A screenshot of the sign-up form on the Ascent website. It contains four input fields: 'Your Name', 'Your email address', 'Comments', and 'How did you hear about ASSENT'. A red 'Sign Up' button is located at the bottom right of the form.

149 registered users in
34 countries

50 project enquires

8 in discussion & review

16 projects supported to
date

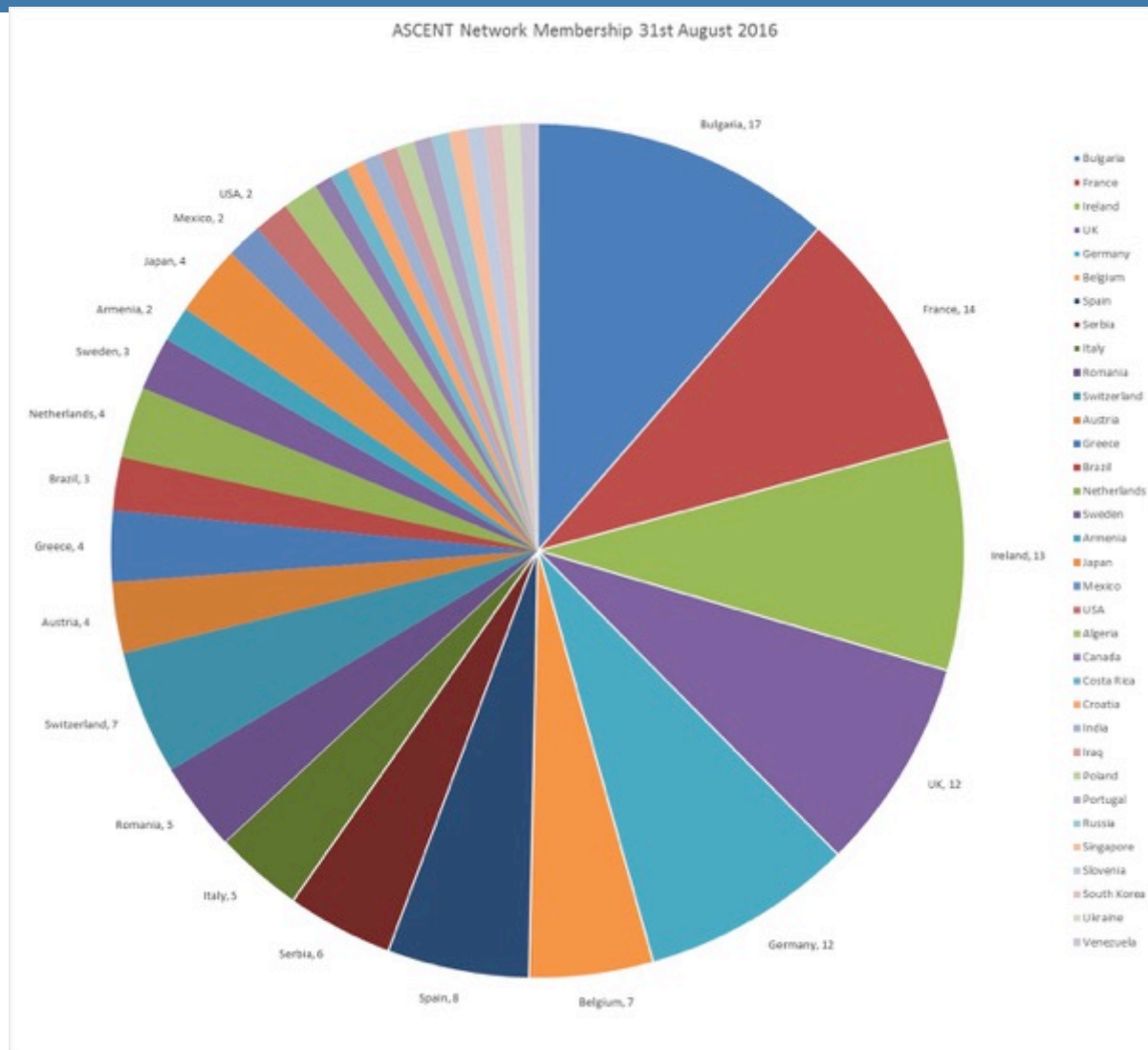
Sign up on-line

-or-

Fill out a card

We'll sign you up

login information will be sent to you



Sign Up

- Free sign up as member
- Discuss with coordinator / technical POC

Apply

- Apply for access to data, chips or equipment
- Selection Panel decides on access

Access

- Access world-leading nanoelectronics technology
- Contribute to Joint Research Activities

ASCENT Project-011 [Access to imec]

- Prof. Ghibaudo, IMEP Grenoble, France
- **Wafers for parameter extraction/characterisation**
- Facilities: Fully processed FinFET device wafers
- Effort/usage: 3 person.day

ASCENT Project-023 [Access to Tyndall]

- Prof. Dragoman, IMT Bucharest, Romania
- **Thin/smooth metal deposition for MIM devices**
- Facilities: Metal deposition + AFM
- Effort/usage: 11 person.day

ASCENT Project-029 [Access to Tyndall]

- Ling Ye, MESA, Univ. Twente, Netherlands
- **Nanowires for monolayer doping**
- Facilities: e-beam lithography, elec. Characterisation
- Effort/usage: 9 person.day

ASCENT Project-030 [Access to Tyndall]

- Prof. Miranda, Univ. Aut. Barcelona, Spain
- **Characterisation of 2D MESFETs (high-k under electrical stress)**
- Facilities: Electrical testing
- Effort/usage: 10 person.day



ASCENT Project-034 [Access to Tyndall]

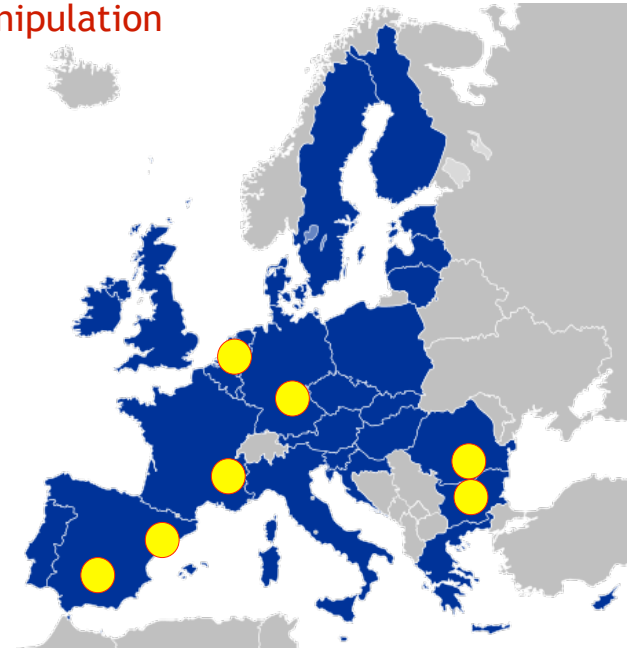
- Prof. Rusev, TU Sofia, Bulgaria
- **Fabrication of acoustic tweezers for nanoparticle manipulation**
- Facilities: Fabrication facilities
- Effort/usage: 9 person.day

ASCENT Project-042 [Access to Leti]

- Prof. Gamiz, University of Granada, Spain
- **Simulation & characterization of SOI devices**
- Facilities: Fully processed FDSOI wafers
- Effort/usage: 15 person.day

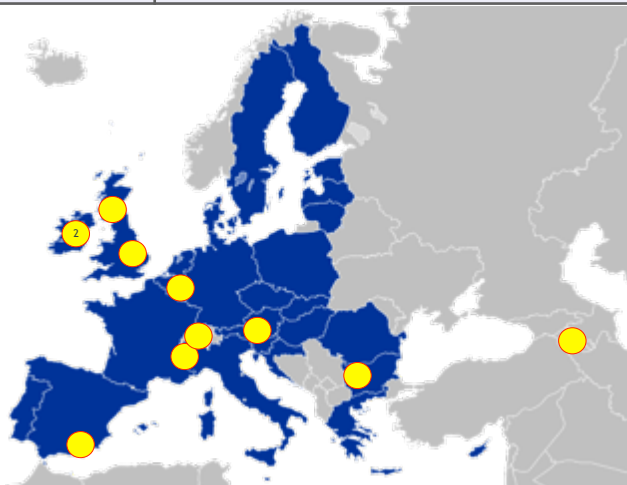
ASCENT Project-050 [Access to Leti]






- Peter Schüffelgen, Forschungszentrum Jülich
- **TEM investigation of topological insulators**
- Facilities: TEM
- Effort/usage: 10 person.day



11 Virtual Access Projects

Ref	User	Institute	Country
002	G. Angelov	Technical University of Sofia	Bulgaria
006	G. Fatin	University of Maynooth	Ireland
008	A. Durgaryan	Synopsys	Armenia
022	A. Nejadmalayeri	Phoelex Ltd (SME)	UK
031	X. Wang	University of Glasgow	UK
035	K. Miyaguchi	IMEC	Belgium
036	G. Ghibaudo	IMEP-LAHC/INPG	France
037	F. Gamiz	University of Granada	Spain
043	M. Karner	Global TCAD Solutions GmbH	Austria
045	T. Kelly	EOLAS Designs	Ireland
047	A. Pezzotta	EPFL ICLAB	Switzerland



Researcher		Institute	Researchers topics/interests	What will you use the CMOS datasets for?
Dr X. Wang		University of Glasgow, UK	<p>Nanoscale MOSFET devices, TCAD and atomistic modeling and numerical simulations</p> <p>Intrinsic parameter fluctuations due to statistical variability and reliability</p>	<p>Develop advanced MOSFET architecture and compact models</p> <p>Currently developing novel statistical compact models</p>
Dr Gholamreza Zare		NUI Maynooth, Ireland	<p>RFIC blocks for a transceiver targeting the next generation of the wireless communications systems</p> <p>High speed data converters, millimetre wave integrated circuits and phased array circuits</p>	<p>I was interested to be able to design with these advanced transistors (FDSOI and FinFET) and investigate their circuit characteristic. I am working on RFIC design and want to know their performance in this design field. This was the main reason to request for access. I am also interested in characterisation of these transistors (chips).</p>
Dr Gerard Ghibaudo		IMEP-LaHC, Grenoble, France	<p>Electronics transport, oxidation of silicon, MOS device physics, fluctuations and low frequency noise and dielectric reliability</p>	<p>Internal needs for PhD students and comparison to other technologies (FDSOI).</p>
Prof. Francisco Gamiz		University of Granada, Spain	<p>Numerical simulators of advanced semiconductor devices</p> <p>Implementation of new transport models, and scattering mechanisms</p>	<p>Calibration and tuning of semiconductor TCAD and home-made simulators.</p>
Prof. George Angelov		Technical University of Sofia, Bulgaria	<p>Device physics; bioelectronics; electrical engineering; multi-physics & control systems; electric vehicles and batteries; renewable energy sources systems; energy efficiency</p>	<p>Matching simulations based on compact models to experiment data.</p>

JRA1: Development of Device Forensic Techniques for <14nm CMOS devices

- Develop new techniques for device forensics of <14nm devices
- Provide data on contaminant impact on device fabrication for <14nm devices and highlight unacceptable materials.
- Recommend test vehicles to enable assessment of new material compatibilities.

JRA2: Standard e-test data and format for VA access

- Engage with user community to discuss and make available standard content for VA
- Work with partners to develop a standardised format for both FDSOI and FINFET technologies for the VA data

JRA3: Benchmarking of electrical characterization methods on new materials

- Develop new techniques for novel material and devices electrical characterization.
- Benchmark methods and results used on the 3 sites for a given set of wafers.
- Recommend most appropriate methods to be used for 5nm nodes and below

	22nm	14/16nm	10nm	7nm
Channel length	25	22	19	16
Fin width	10	9	8	7
Fin height	34	42	~50	50+
Aspect ratio	3 : 1	5 : 1	6 : 1	7 : 1

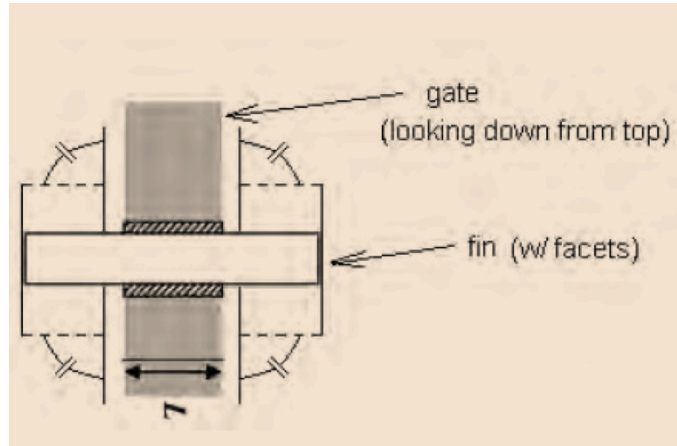
} L/W ratio ~2.5



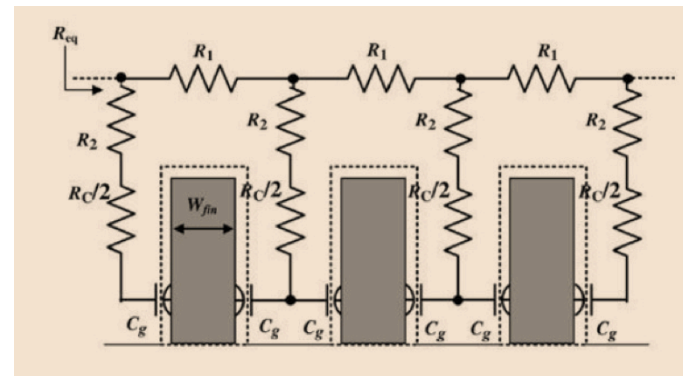
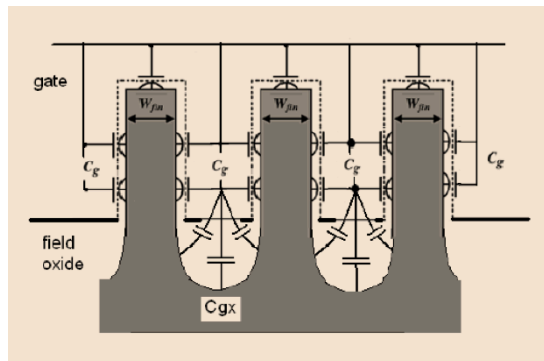
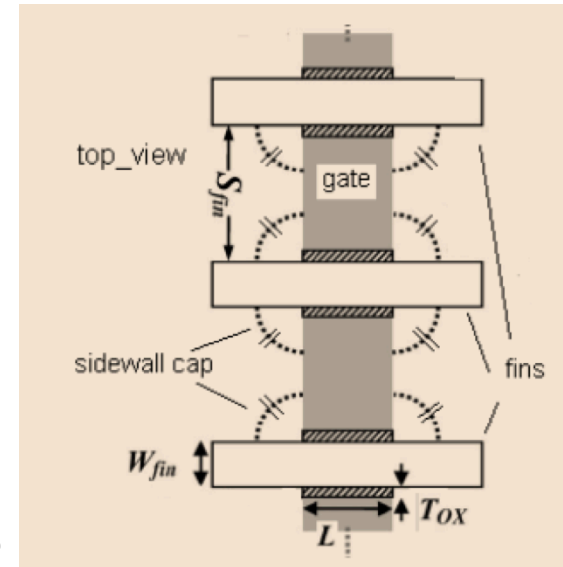
© 2016 Synopsys, Inc. 15

ISPD 2016, Santa Rosa, California

SYNOPSYS

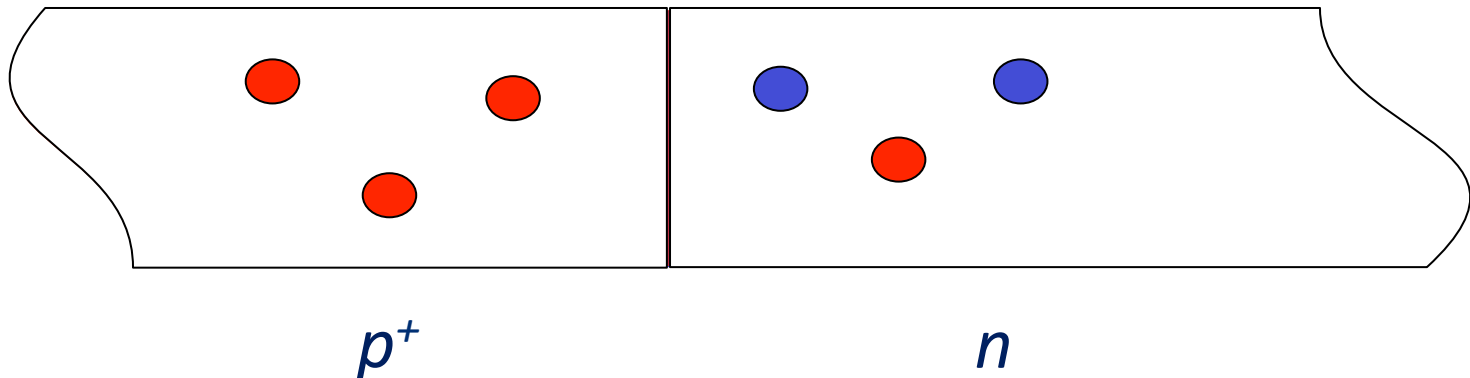


Gate to source/drain sidewall capacitance



Gate access resistance

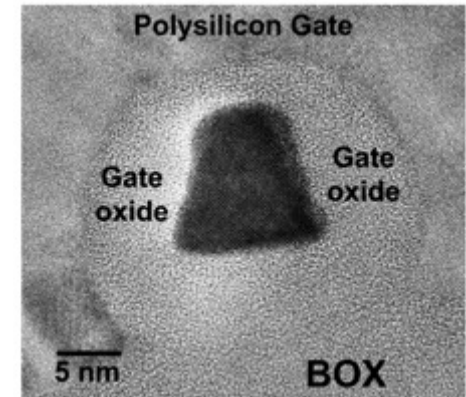
NW dimensions/ nm ³	Atoms/ nanowire volume	Atoms/ nanowire length	Dopant atoms/ nanowire
60x20x20	1,200,000	222	1200
30x10x10	150,000	111	150
15x5x5	18,750	55	□ 20
6x2x2	1,200	22	□ 1



- ✓ No junctions, no doping gradients
- ✓ Gate lengths 50nm, 20 nm, 3 nm fabricated!

The cross-section of the channel needs to be small enough gate can entirely **deplete the heavily doped channel** to turn the device off

... and requires **high doping concentration** for good “current drive”



nature
nanotechnology

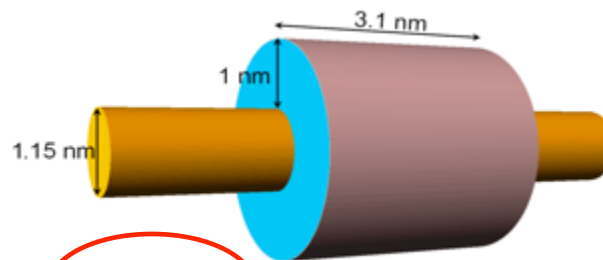
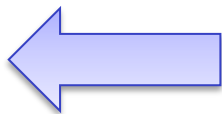
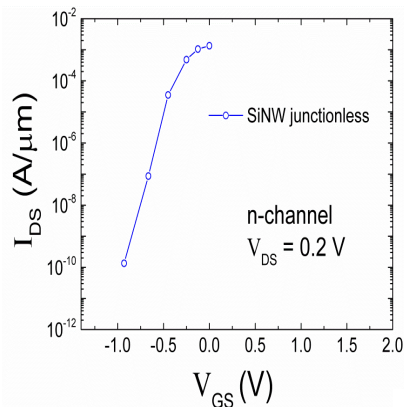
ARTICLES

PUBLISHED ONLINE: 21 FEBRUARY 2010 | DOI: 10.1038/NNANO.2010.15

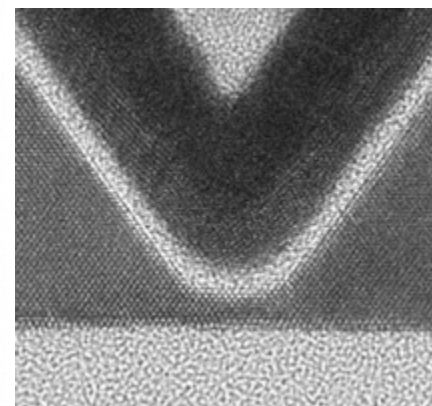
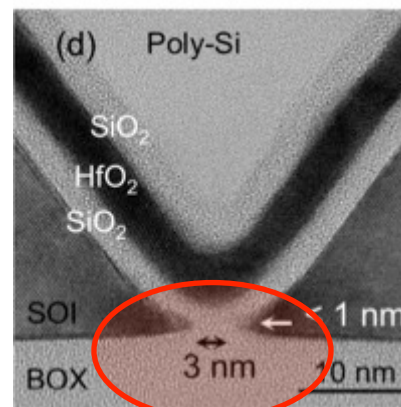
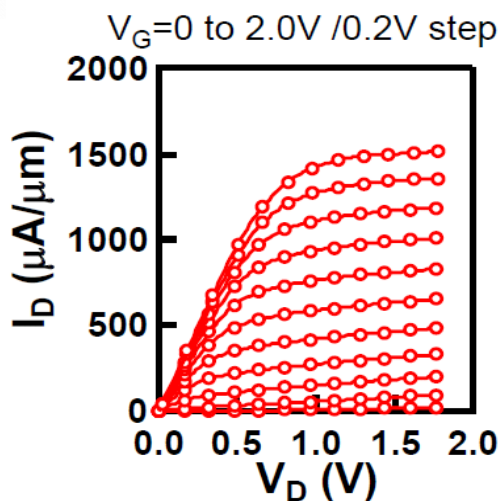
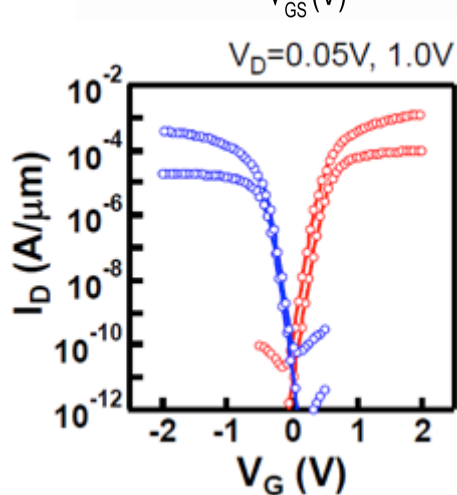
Nanowire transistors without junctions

Jean-Pierre Colinge*, Chi-Woo Lee, Aryan Afzalian†, Nima Dehdashti Akhavan, Ran Yan, Isabelle Ferain, Pedram Razavi, Brendan O'Neill, Alan Blake, Mary White, Anne-Marie Kelleher, Brendan McCarthy and Richard Murphy

All existing transistors are based on the use of semiconductor junctions formed by introducing dopant atoms into the semiconductor material. As the distance between junctions in modern devices drops below 10 nm, extraordinarily high doping concentration gradients become necessary. Because of the laws of diffusion and the statistical nature of the distribution of the doping atoms, such junctions represent an increasingly difficult fabrication challenge for the semiconductor industry. Here, we propose and demonstrate a new type of transistor in which there are no junctions and no doping concentration gradients. These devices have full CMOS functionality and are made using silicon nanowires. They have near-ideal subthreshold slope, extremely low leakage currents, and less degradation of mobility with gate voltage and temperature than classical transistors.



L. Ansari et al., Applied Physics Letters, **2010**
L. Ansari et al., Solid State Electronics, **2012**

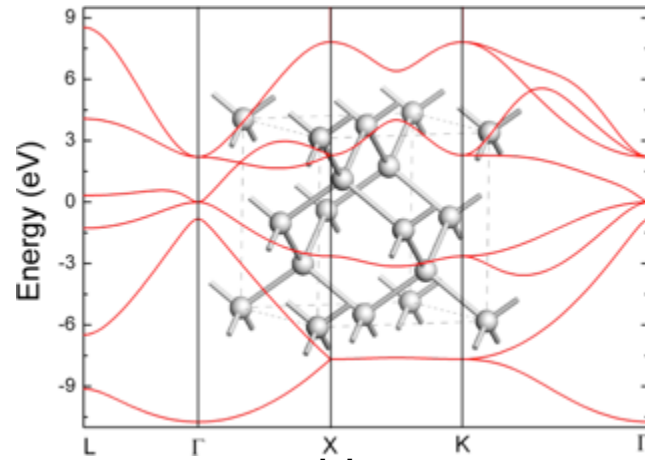


Fabrication and Demonstration of 3-nm-Channel-Length Junctionless Field-Effect Transistors on Silicon-on-Insulator Substrates Using Anisotropic Wet Etching and Lateral Diffusion of Dopants

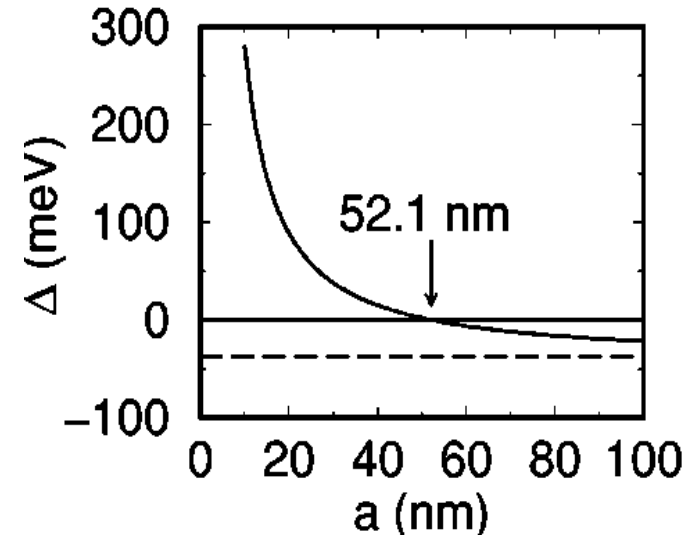
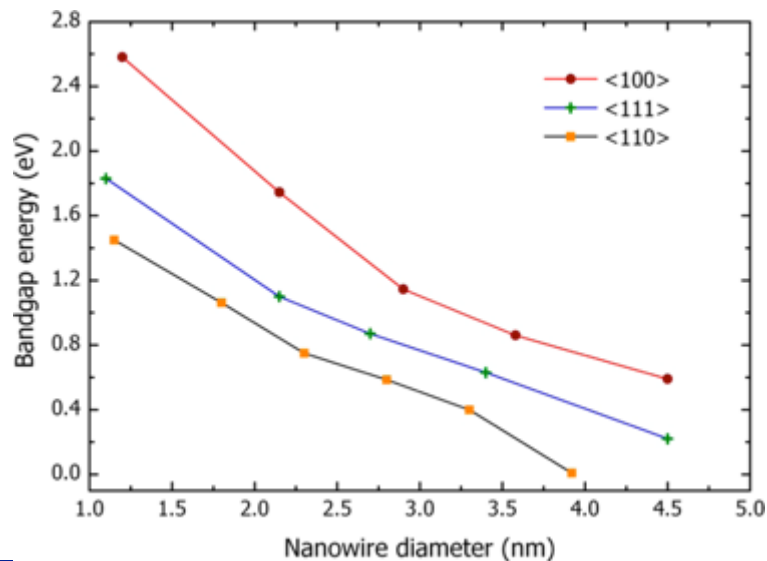
Shinji Migita*, Yukinori Morita, Meishoku Masahara, and Hiroyuki Ota

Japanese Journal of Applied Physics **52** (2013)

Quantum alchemy: semimetal to semiconductor transition

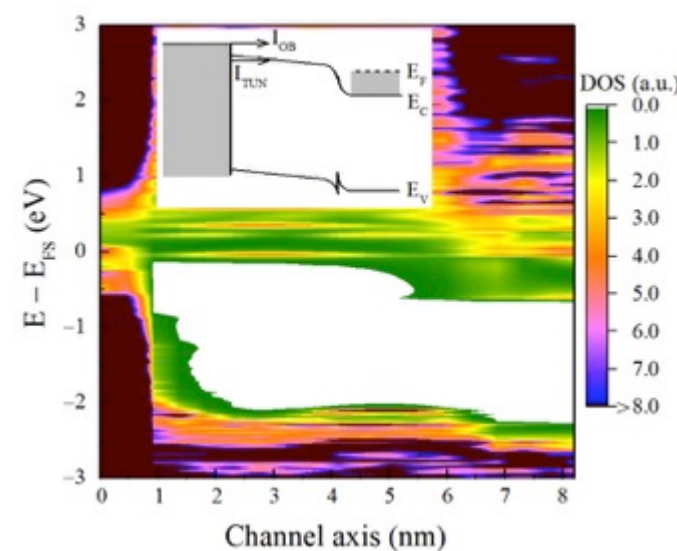
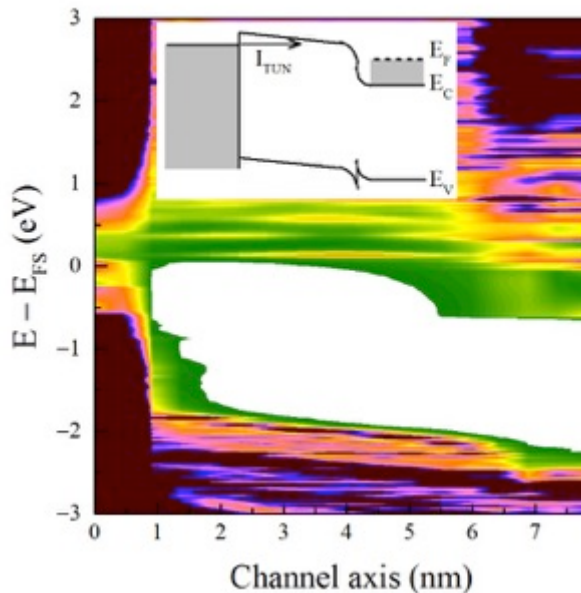
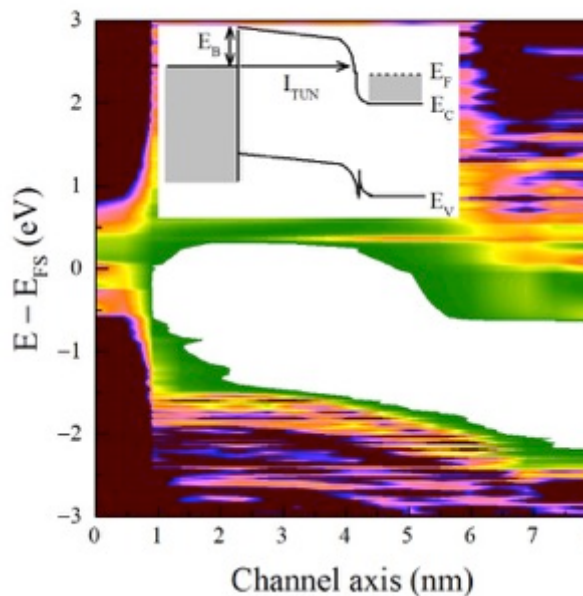
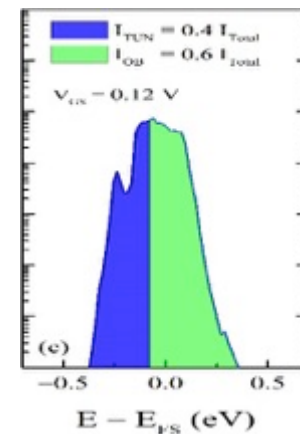
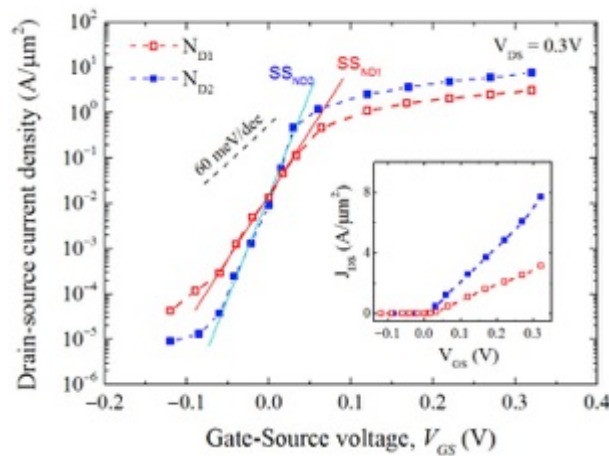
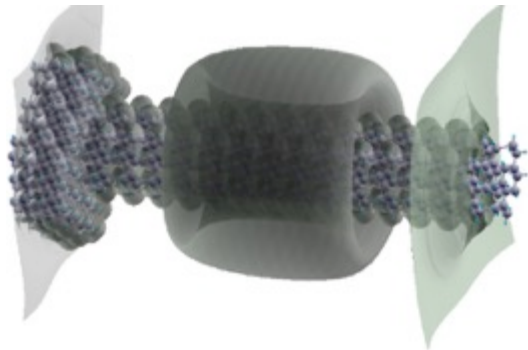


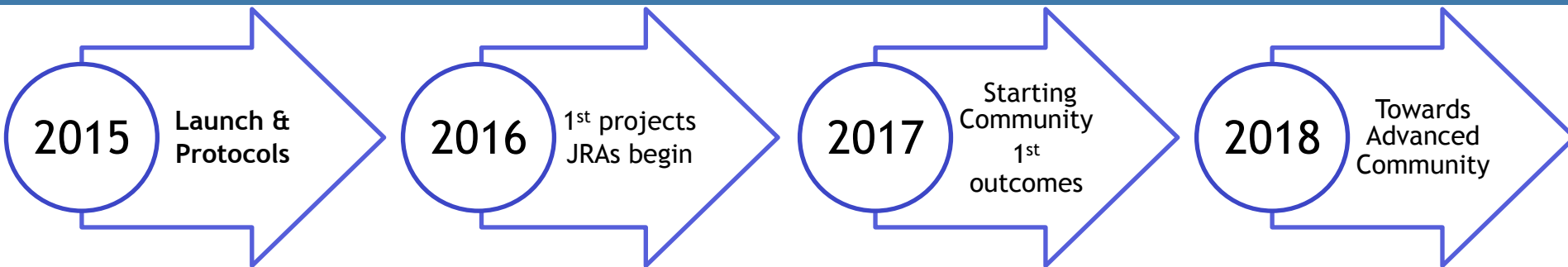
metastable α -tin



Theoretical description for bismuth:
Sin, Zhang, Dresselhaus,
Appl. Phys. Letters 1999

**Instead of fighting
quantum effects,
can we make them
work for us?**





Explore an access proposal

- Advanced CMOS: 14 nm FinFET and planar FDSOI
- Nanowire & Novel devices
- Novel materials and processes

Open to commercial (ma & pop, SMEs, MNCs), RTOs, universities
Worldwide!

Costs for approved access projects covered

Overall Access Team Objectives:

- Define an easy access model for the User Community
- Generate data libraries, test-chips, equipment access capability
- Establish access route through single point of contact
- Establish & manage Selection Process - 1 week turn around!
- Provide logistical support for virtual and transnational access
- Analyse user profiles, requirements, outputs and impacts

We will follow up with all registered attendees after the Workshop
and invite you to sign up as members of ASCENT

www.ascent.network

or email

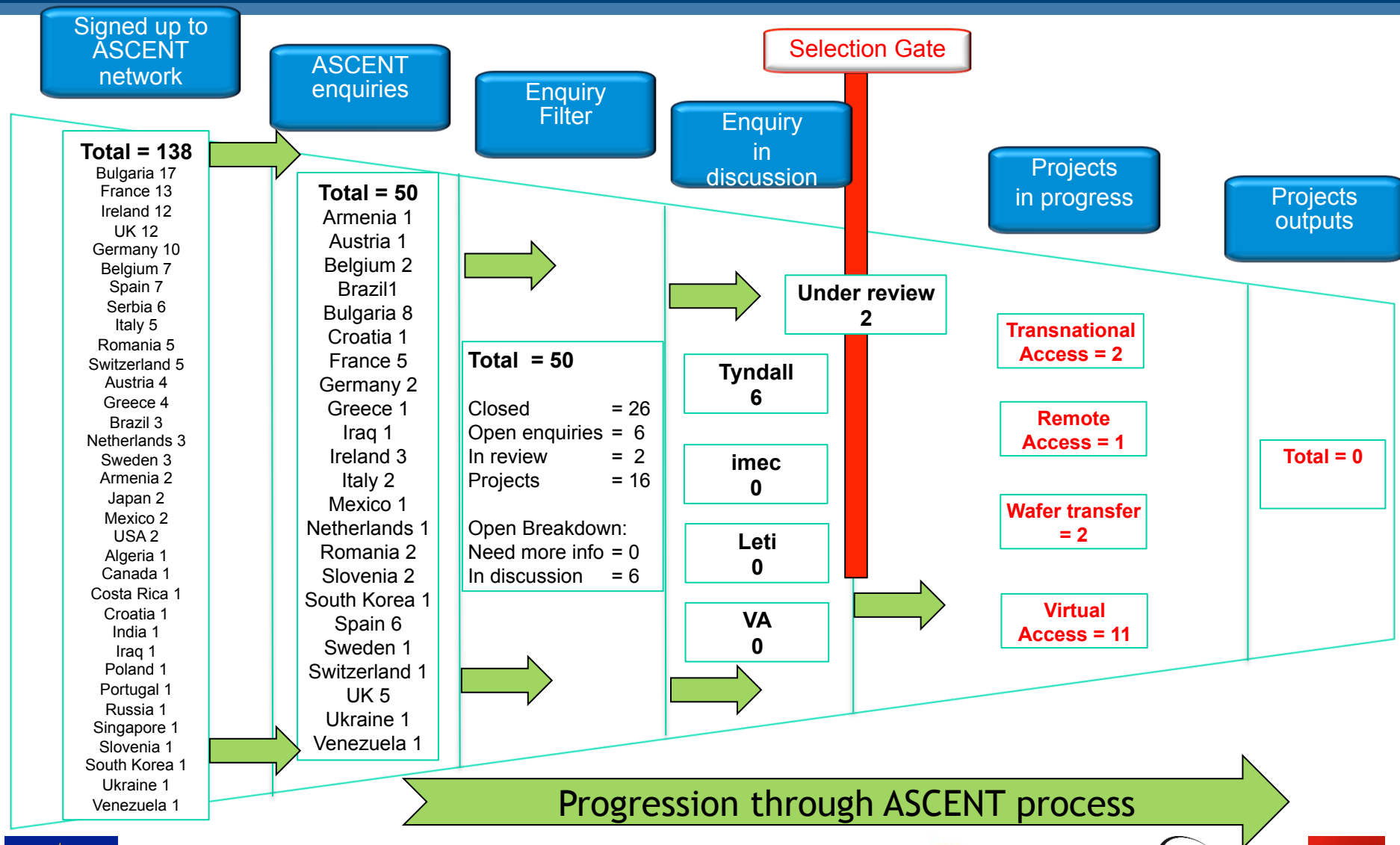
or phone

Paul Roseingrave: +353-21-2346168

and join with us in this exciting opportunity for nanoelectronics
research







- Structure generation and physical characterisation of test structures
- Ab initio simulation time: months
 - yet TCAD typically hours or overnight
- Electrical characterization and relate to device to device variability
- Capture new physics and device variability in compact models